N76 12502

SURFACE SCIENCE APPLIED TO THE DEVELOPMENT OF ECONOMICAL PHOTOVOLTAIC SOLAR CELLS

- 1) The effect of dopants on chemical vapor deposition a surface potential model.
- 2) Surface segregation of impurities.
- 3) Silicon recrystallization using a thin Al layer on carbon.
- 4) Effect of structure and impurities on surface states.

SURFACE STRUCTURE AND ELECTRONIC PROPERTIES OF MATERIALS

AG 742 \$ 87,500

Jan. 1, 1975 - July 1, 1975

W. J. Siekhaus

Energy and Environment Division Lawrence Berkeley Laboratory

G.A. Somorjai

Inorganic Materials Research Division Lawrence Berkeley Laboratory

AVS - Chicago 1974

.

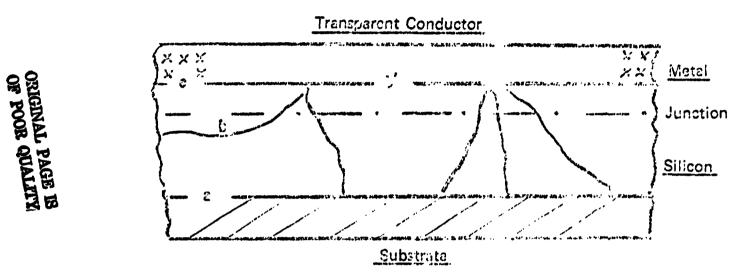
ASME - Palo Alto 1974

ACS - Chicago

International Sum mer Course - Procidia, Sicily 1975

An economically competetive solar cell consists of a substrate on which $a \rightarrow 00 \mu$ thick silicon layer is deposited, covered by a transparent conductor containing a metallic grid.

The problems to which research is directed are identified in the cell by the letters a, b, b', c.



Research Areas:

a) Low temperature catalysis of the decomposition of SiH₄, SiCl₄ on a low maiting point substrate material (e.g. Al) to form large area silicon shoats.

Research tool: molecular beam deposition.

b) Catalysis of large grain crystallization by use of suitable impurities.

Segregation of impurities onto grain boundaries.

Research tool: Icw energy electron diffraction, Auger spectroscopy.

a,b,b',c. Dependence of electronic surface states on impurities.

Research tool: photoelectron spectroscopy, energy loss spectroscopy.

••••

.

PROGRAM OBJECTIVE

ANALYZE INFLUENCE AND BEHAVI AND INTERFACES DURING CVD FILM DEPOSITION EFG SHEET FORMATION CELL LIFE

DETERMINE AND LEARN TO UNDERSTAND, TO CORRECT AND TO USE THE EFFECT OF CHEMICAL COMPOSITION AND PHYSICAL STRUCTURE OF SURFACES AND INTER-FACES ON ELECTRONIC STATES.

٠

The objective of this grant is to employ surface science to the problems associated with the development of economical thin film solar cells: to understand and control the mechanism of chemical vapor deposition, to study substrate - film interaction, to analyze impurity segregation onto surfaces and grain boundaries, to determine the effect of selected impurities on grain growth and to investigate the effect of structure and impurities onto surface states.

We have developed a surface potential model to explain dopant effects on chemical vapor deposition. Auger analysis of the interaction between allotropic forms of carbon and silicon films has shown Si-C formation for all forms but glassy carbon. LEED intensity measurements have been used to determine the mean sqare displacement of surface atoms of silicon single crystals, and electron loss spectroscopy has shown the ϵ ffect of structure and impurities on surface states located within the band gap. A thin film of Al has been used to enhance film crystallinity at low temperature.

At the present time we perform chemical vapor deposition under externally applied electric fields to test the surface potential model of chemical vapor deposition. We use Auger spectroscopy to identify impurities segregating onto surfaces and interfaces, and we are investigating with electron loss spectroscopy the effect of do- nts on surface states.

Future experiments are planned to determine dopant spatial distribution on the surface during chemical vapor deposition, the effect of dopants on chemical vapor deposition reaction kinetics using modulated molecular beam analycis, and the effect of impurities on the activation energy for recrystallization. We plan to use UV electron spectroscopy together with improved energy resolution electron loss spectroscopy to determine absolute energy levels of impurity induced surface states.

621

WORK PLAN

| WORK AREA | PROGRAM | RESULTS |
|---------------------------|---|---|
| Surface states | LEED intensity data on (111) and (7x7(111) Si | Thesis published. Shows correlation between recon- struction and change in bond strength. |
| | Electron loss spectra on Si(2xl)(111) Si and amor- phous Si. | Report. Shows removal of surface state in midgap by oxygen adsorption. |
| Impurity segre- gation | Fracture and analyze large and small grain polycrystal line Si to determine grain boundary impuritegre- gation. | Report. Difficulties. Si does not reproducibly fracture along grain boundaries. Almost always cleaves. Change experimental procedure. |

WORK PLAN

•

.

з

| WORKAREA | PROGRAM | RESULTS |
|---|---|---|
| Effect of Al on Si crystallinity | Thin layer of Al on C be- fore Si deposition | LB L report. Good crystallinity at low temperature without SiC formation. |
| Effect of surface charge on deposition | Equipment modification and first measurements. | LBL report, theoretical model submitted for publication. |
| Analytical work for other groups. | "Get" scanning Auger Analyzing system | "Got" it. Measured boron distribution in ion implanted Si. |

.

GRAIN BOUNDARY SEGREGATION OF BORON IN POLYCRYSTALLINE FILMS.

Experimental results reported in J.Electr.Chem.Soc. (first graph - page suggest, that in chemical vapor deposition together with Boron doping the grain boundary will be completely covered with a monolayer of dopant before doping in the grain can be achieved.

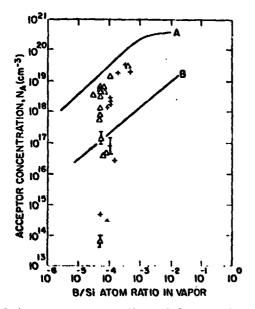
To check this hypothesis, polycrystalline films were deposited onto single crystal substrates covered with a thin nitride layer. Deposition was done by CVD using SiCl with B H doping by 4 26 Applied Materials Corporation to a thickness of 200 Å. Estimated 18 concentration of B is 6.6 x 10 /cm³.

The next few graphs show, that polycrystalline silicon, under the conditions investigated up to now almost exclusively fractures by cleavage.

Consequently, Scanning Auger Analysis of fractured surfaces allows up to now no consistent analysis of grain boundary segregation.

/ Efforts continue to find suitable conditions, and an alternate approach to find surface segregation is presented in the next section./

624



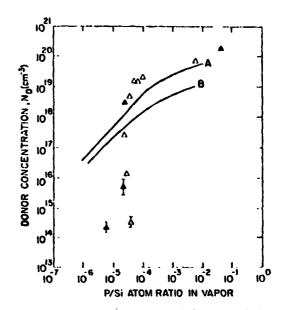


Fig. 2. Acceptor concentration, N_A , vs. B/Si atom ratio in vapor for paly Si samples deposited from SiH₄ at 650°C. \triangle , Thermal SiO₂ substrates; +, fused quartz substrates. Single-crystal doping: , boron doping of Si from B₂H₆ and SiCl₄-H₂ at 1500°K, A (11); B (12).

Fig. 3. Donor concentration, N_D, vs. P/Si atom ratio in vapor for poly Si samples deposited an thermal SiO₂ substrates. \triangle Deposited at 650°C from SiH₄, \triangle deposited at 840°C from SiBr₄·H₂. Phosphorous-doped single-crystal silicon, A (14); B (12).

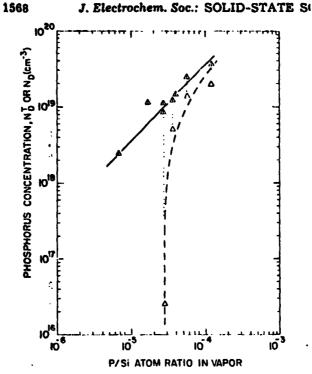
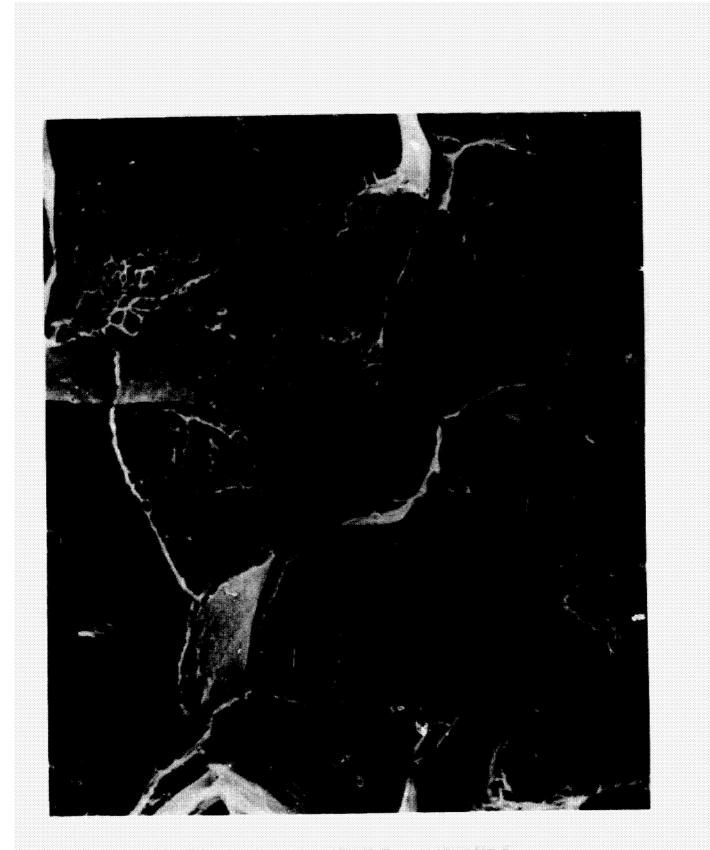


Fig. 4. Total phasphorous concentration, N_DT , and donor concentration, N_D , vs. P/Si atom ratio in vapor for poly Si deposited from SiH₄ at 650°C. A Total phosphorous concentration, Δ donor cancentrations, ——— see Eq. [1] in text, ---- calculated from Eq. [4] in text.

M.E. Cowher and T.O. Sedgwick, J. Electrochem. Soc., SSS&T, Nov. 1972

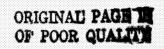


Mysical Crein Boundary fracture of Fe-12 Mas 0.2 Ti, 1900 X

ORIGINAL PAGE IS OF POOR QUALITY

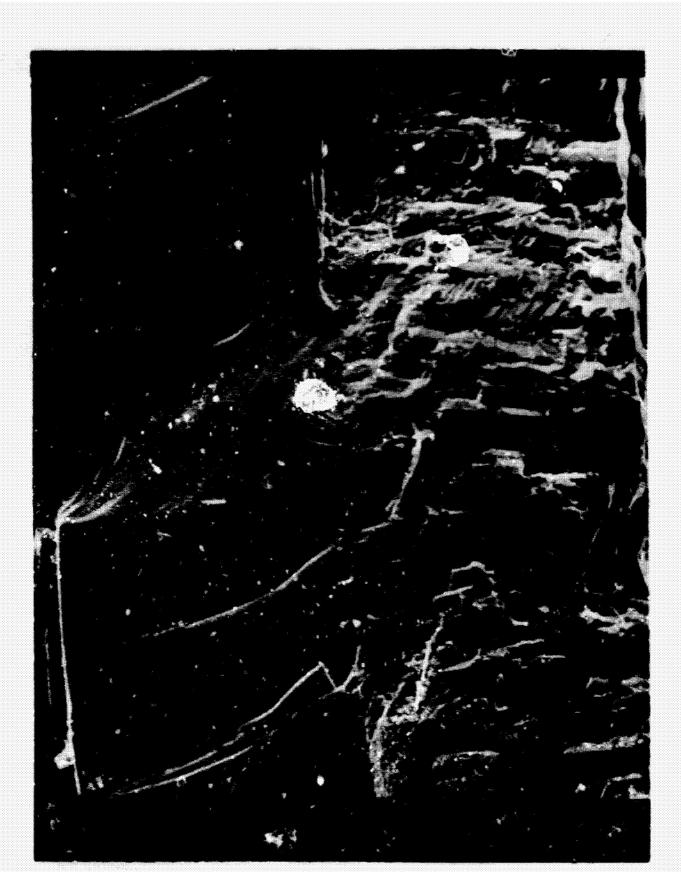


S fince of Pol, ____ on Siliconnitrile (1000X)





FRACTURE VIEW OF POLYCRYST, SILICON CLOSE TO SURFACE, (600)



FRACTURE VIEW OF POLYCE, SI FILM ON SI. 1 OF NITRIDE (00 X)

